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JRW*

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Van Schravendijk, et al

Attorney Docket No.:

NOVLP037C1/NVLS-000519C1

Application No.: 10/773,821

Examiner: UNASSIGNED

Filed: February 5, 2004

Group: 2813

Title: APPLICATIONS AND METHODS OF
MAKING NITROGEN-FREE ANTI-
REFLECTIVE LAYERS FOR
SEMICONDUCTOR PROCESSING

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on May 11, 2004 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: _____

Leslie Russell
Leslie Russell

REQUEST FOR CORRECTED FILING RECEIPT

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Alexandria, VA 22313-1450

Sir:

Enclosed is a copy of the Filing Receipt for the above-identified patent application. Please reprint the Filing Receipt as follows and mail the corrected copy to the undersigned.

Change Applicant "M. Zlraul Karim" to -- M. Zi~~a~~ul Karim --.

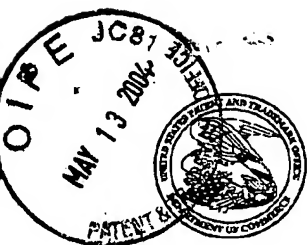
Since this is a Patent Office typographical error, no fee should be due. However, the Commissioner is authorized to charge any fees that may be due to Deposit Account 500388 (Order No. NOVLP037C1).

Respectfully submitted,
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/773,821	02/05/2004	2813	770	NOVLP037C1/NVLS-000519C1	5	9	3

CONFIRMATION NO. 8057

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FILING RECEIPT



OC000000012538268

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Assignment For Published Patent Application

Novellus Systems, Inc.;

Domestic Priority data as claimed by applicant

This application is a CON of 09/990,197 11/21/2001 PAT 6,720,251
 which claims benefit of 60/302,112 06/28/2001

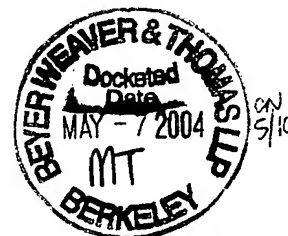
Foreign Applications

If Required, Foreign Filing License Granted: 05/05/2004

Projected Publication Date: Request for Non-Publication Acknowledged

Non-Publication Request: Yes

Early Publication Request: No



TJW

Title

Applications and methods of making nitrogen-free anti-reflective layers for semiconductor processing

Preliminary Class

438

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